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IN THE UNITED STATES
PATENT AND TRADEMARK OFFICE

PATENT APPLICATION

Applicant: Chou, et al.

Serial No.: 10/026,378

Examiner: Not yet assigned

Title: **METHOD OF TISIN DEPOSITION USING A CHEMICAL VAPOR
DEPOSITION PROCESS**



Case: 761/P11

Filed: December 21, 2001

Group Art Unit: 1702

ASSISTANT COMMISSIONER FOR PATENTS
Washington, DC 20231


SIR:

SUBMISSION OF FORMAL DRAWINGS

The Applicants submit herewith 8 sheets of formal drawings (FIGS. 1 through 5D) in connection with the above-captioned application.

Respectfully submitted,

6/10/02


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